

Course

LMK - Light microscopy

Version: 1 | Last Change: 19.09.2019 15:08 | Draft: 0 | Status: vom verantwortlichen Dozent freigegeben

^

General information

Long name	Light microscopy
Approving CModule	LMK BaET LMK BaET
Responsible	Prof. Dr. Stefan Altmeyer Professor Fakultät IME
Level	Bachelor
Semester in the year	winter semester
Duration	Semester
Hours in self-study	78
ECTS	5
Professors	Prof. Dr. Stefan Altmeyer Professor Fakultät IME
Requirements	mathematics; vector calculus complex numbers physics / optics: geometrical optics wave optics
Language	German
Separate final exam	Yes

Final exam

Details

As long as the number of participants is not too high, oral examination is preferred of written exams.

Lowest competence level checked is knowledge. This could be e.g. structural components that are present in every microscope, the raypath of a transmission and a reflexion microscope with Köhler illumination, the location of the angular apertur and the phase ring in a Zernike phase microscope or the reason for the direction selectivity in a differential interference contrast microscope.

The next competence level is related to skills. Examination could be done by the calculation of required parameters of key components in a microscope, either on the basis of given application specifications or by the specification of some components, that are already in use. Furthermore it can be checked, if the setup of Köhler illumination can be explained, ideally with explanatory statements.

The highest competence level adressed is methodical expertise. It can be checked by the discussion of a real world task: E.g.: Determine the radius of curvature of a lens. Here the choice of the right type of microscope is already important. Furthermore the process of data acquisition and the data manipulation good methodical expertise. Another task could be to measure quantitatively the relative phase shift of two structures in an object.

Minimum standard

Correct answer of at least 50 % of the questions

Exam Type

As long as the number of participants is not too high, oral examination is preferred of written exams.

Lowest competence level checked is knowledge. This could be e.g. structural components that are present in every microscope, the raypath of a transmission and a reflexion microscope with Köhler illumination, the location of the angular apertur and the phase ring in a Zernike phase microscope or the reason for the direction selectivity in a differential interference contrast microscope.

The next competence level is related to skills. Examination could be done by the calculation of required parameters of key components in a microscope, either on the basis of given application specifications or by the specification of some components, that are already in use. Furthermore it can be checked, if the setup of Köhler illumination can be explained, ideally with explanatory statements.

The highest competence level adressed is methodical expertise. It can be checked by the discussion of a real world task: E.g.: Determine the radius of curvature of a lens. Here the choice of the right type of microscope is already important. Furthermore the process of data acquisition and the data manipulation good methodical expertise. Another task could be to measure quantitatively the relative phase shift of two structures in an object.

^ Lecture

Learning goals

Knowledge

depth of field
paraxial, on the object side
near and far point
hyperfocal distance
wace optical, on the image side

amplitude- and phase objects
law of Lamberr-Beer
optical density
phase, refraction index and optical distance
Abbe's theory of image formation
relative phase of diffraction orders

of amplitude objects

of phase objects

phase microscope

with phase disc

location and size of zero'th diffraction order

spatial coherence

diffraction artefacts

Zernike

location and size of zero'th diffraction order

spatial coherence

the principle of Babinet

diffraction artefacts

visibility and contrast

attenuation in the phase ring

coherence

visibility of interference

temporal coherence

length of wavetrains

spectral composition of wavetrains

time shifted arrival of amplitude split wavetrains

fast change of interference patterns

coherence time

spatial coherence

spatially split wavetrains

phase shift in spatially split wavetrains in dependence of the location of the origin

spatial overlay of interference patterns

spatial coherence length

interferometer

Michelson

compensation plate

second interference pattern

Mach-Zehnder

phase shifts on reflexions

complementary interference patterns

contrast of unequal splitted wavefronts

ambiguity of interference patterns

white light interferometer

interference colors and contrast function

interference microscope

Linnik

sorted pairs of objectives

Michelson

long work distance objectives

Mirau

Schwarzschild objectives

differential interference contrast

birefringence

modification of Huygens' principle

indicatrix

Wollaston-, Nomarski- and Smith prisms

splitting below resolution

interference colors

base optical path difference and lambda plate
coherence requirements in the DIC
temporal
spatial
transmission-interference microscopes
Leitz' Mach-Zehnder interference microscope
interphaco microscope

Skills

- calculate depth of field
- convert optical density, dynamic in images and absorption coefficients into on another
- determine phase discontinuities at interfaces quatitatively
- calaculate sizes of phase rings and angular apertures of Zernike phase microscopes
- calculate the strength of diffraction orders and derive image contrast from them
- estimate temporal coherence from bandwith of frequencies and wavelengths and vice versa
- estimate spatial coherence from lightsource size and distance and vice versa
- draw ray paths of the different interference micorscopes and explain them
- calculate the requirements regarding coherence in the different interference microscopes
- calculate geometries from ackquired interferograms
- predict colors in white light interferometry
- explain and compare physically and technically the underlying principles of different microscopes

Expenditure classroom teaching

Type	Attendance (h/Wk.)
Lecture	2
Tutorial (voluntary)	0

Separate exam

none

Learning goals

Skills

- set up Köhler illumination
- balancing lengths and angles in interferometers
- prepare objects for microscopy
- set up, adjust and use microscopes, especially
 - bright field
 - dark field
 - reflexion
 - transmission
 - Zernike phase contrast
 - Linnik interference contrast
 - differential interference contrast
- choose a suitable microscopy principle for a given object and task
- tell artefacts from object details
- judge image quality
- write scientific report
- describe the task
- describ the idea of the solution
- explain the experimental setup
- explain the data processing
- make error analysis
- present the results and make a critical discussion

Expenditure classroom teaching

Type	Attendance (h/Wk.)
Practical training	2
Tutorial (voluntary)	0

Separate exam

Exam Type

working on projects assignment with your team e.g. in a lab)

Details

1) Written examination questions related to the experiment have to be prepared at home and shown at the beginning of the laboratory.

2) The underlying ideas of the experiment have to be explained at the beginning of the laboratory.

3) Make the experiment alone (preferred) or in a team of two.

- Build up and adjust your own setup
- Acquire / measure data with this setup

4) Write a documentation on the experiment. It will be checked with regard to

- completeness
- scientific and precise language
- correctness
- understanding of the interrelations and interpretation of the results

Minimum standard

All written tasks must have been dealt with.

The basic ideas of the experiment must have been understood.

All experiments must have been performed.

The reports must be free of systematical errors.